



Dr. Sandip Halder

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Sandip Halder received his Ph. D degree in Metallurgy and Materials Science from RWTH Aachen in 2006. He joined IMEC in 2007 and started to work as a researcher on optical metrology and defect detection in advanced CMOS processes. Between 2010 -2014, he led the metrology and inspection pathfinding activities for the 3D heterogenous integration program at imec. In 2014 he joined the Advanced Patterning Department at imec as a senior researcher. During this period, he focused on the development of process window expansion methods together with various equipment vendors for advanced integration flows. Between the period 2016-2020 he led the process control and inspection teams within the Advanced Patterning Department. From 2020 he became the group lead of the Advanced Patterning Solution Group. During 2023-2024, he took on the role of R&D Strategy Manager at SCREEN SPE at imec. As of 2024 he rejoined imec as group lead for Advanced Litho Process Solutions. He has more than 150 papers and filed 12 patents in the field of inspection and metrology and process control.